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(54) **THERMALLY SHORTED BOLOMETER**

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H01L 2924/1461 (2013.01)

(71) Applicant: **Robert Bosch GmbH**, Stuttgart (DE)

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(72) Inventors: **Gary O'Brien**, Palo Alto, CA (US);
Fabian Purkl, Gerlingen (DE); **Ando Feyh**, Reutlingen (DE); **Bongsang Kim**,
Mountain View, CA (US); **Ashwin K Samarao**, Mountain View, CA (US);
Thomas Rocznik, Mountain View, CA (US); **Gary Yama**, Mountain View, CA (US)

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(73) Assignee: **Robert Bosch GmbH**, Stuttgart (DE)

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(74) *Attorney, Agent, or Firm* — Maginot Moore & Beck
LLP

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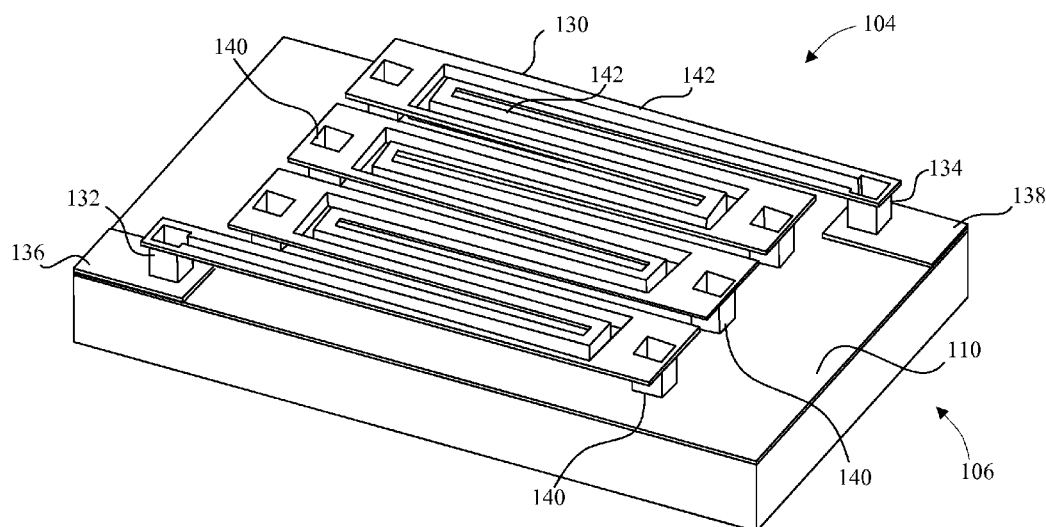
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ABSTRACT

In one embodiment, A MEMS sensor assembly includes a substrate, a first sensor supported by the substrate and including a first absorber spaced apart from the substrate, and a second sensor supported by the substrate and including (i) a second absorber spaced apart from the substrate, and (ii) at least one thermal shorting portion integrally formed with the second absorber and extending downwardly from the second absorber to the substrate thereby thermally shorting the second absorber to the substrate.

20 Claims, 5 Drawing Sheets



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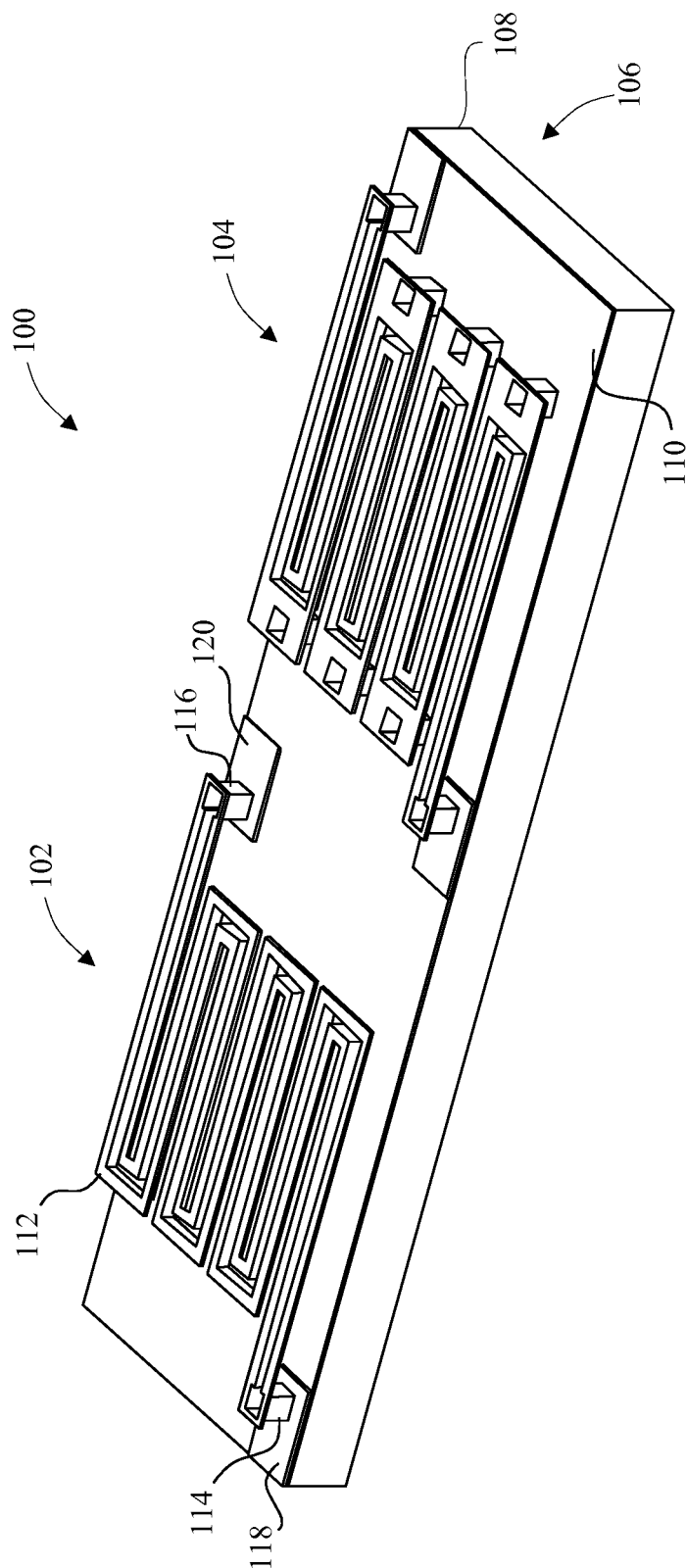


FIG. 1

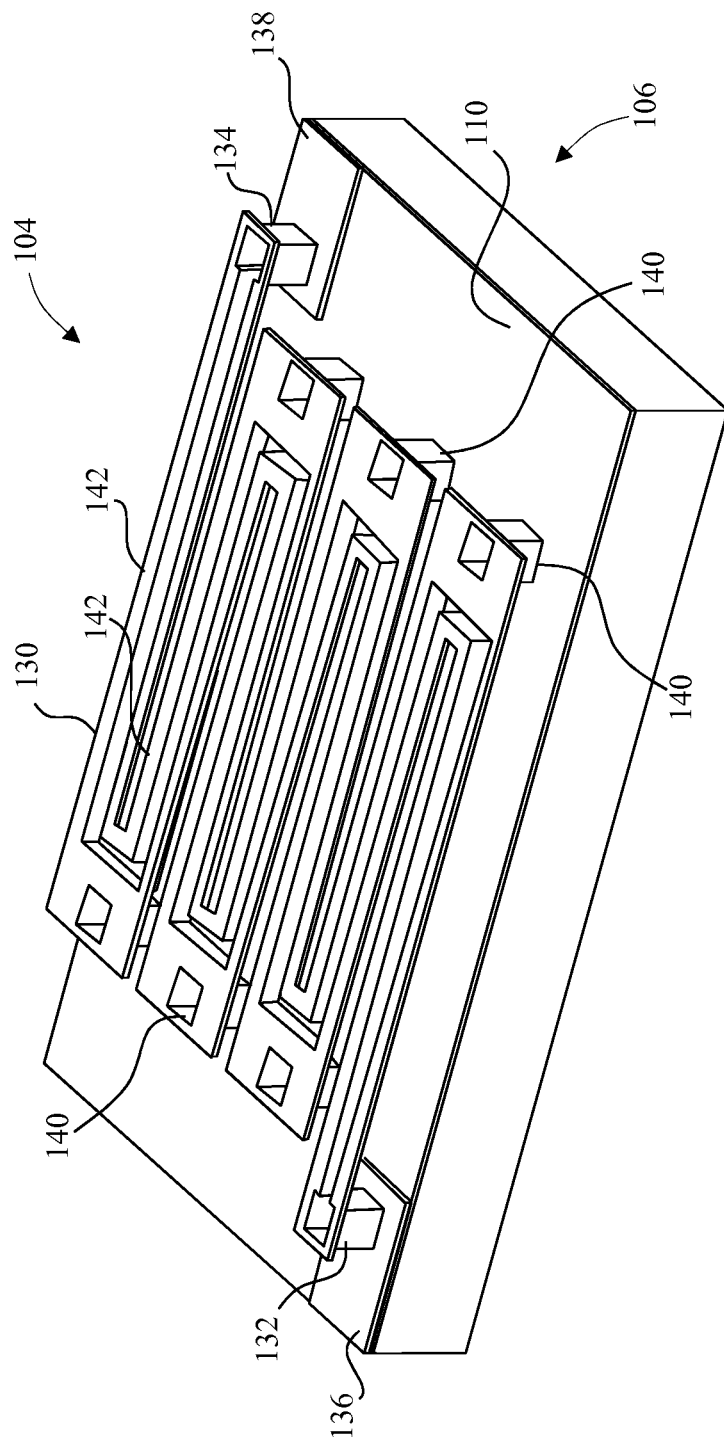


FIG. 2

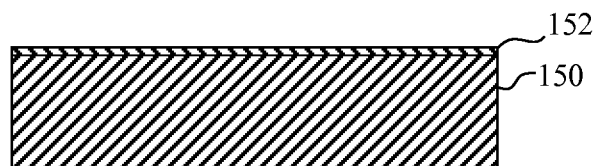


FIG. 3

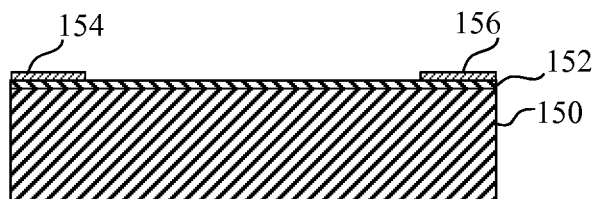


FIG. 4

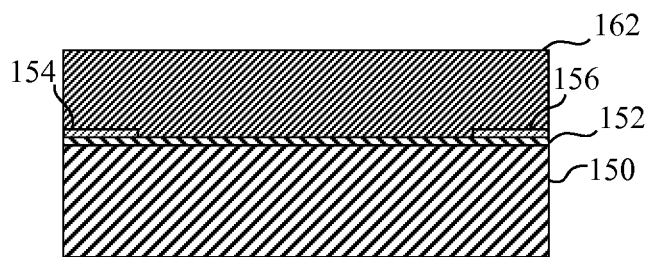


FIG. 5

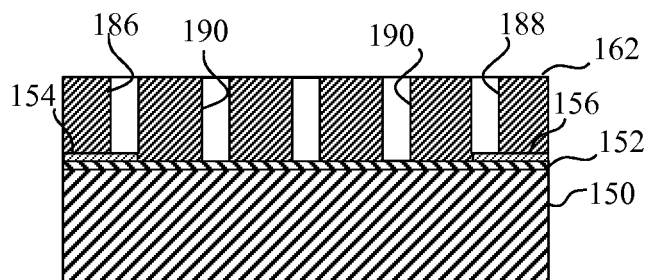


FIG. 6

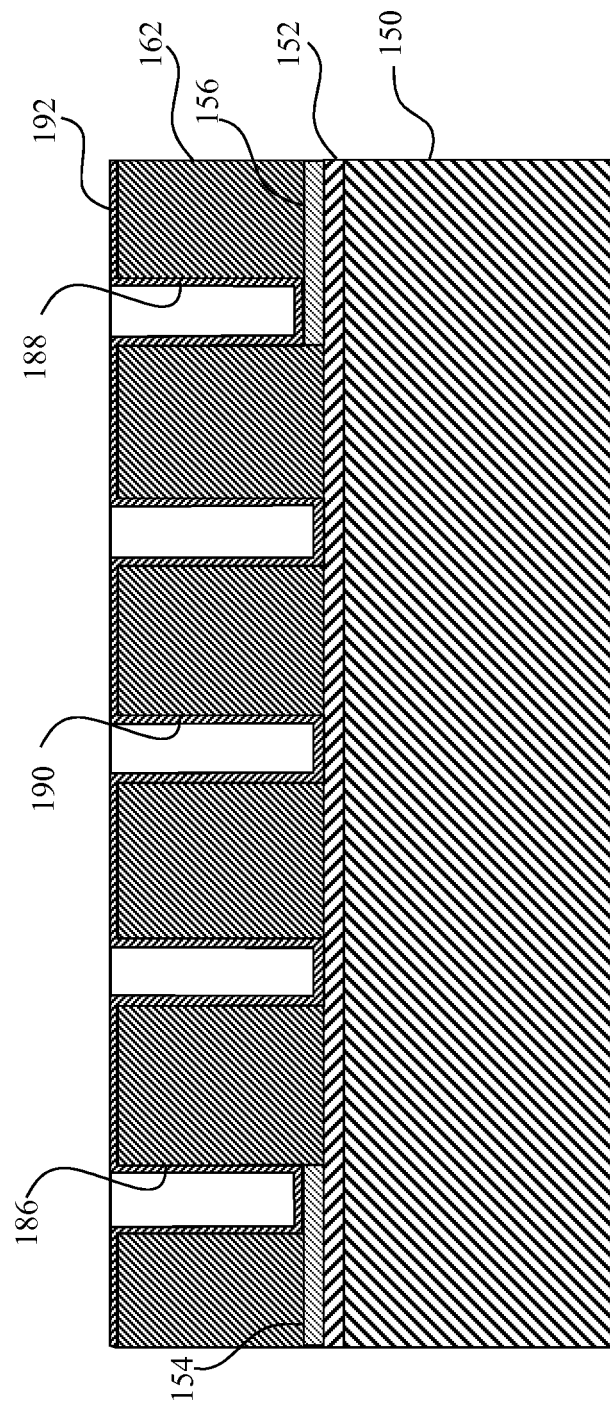


FIG. 7

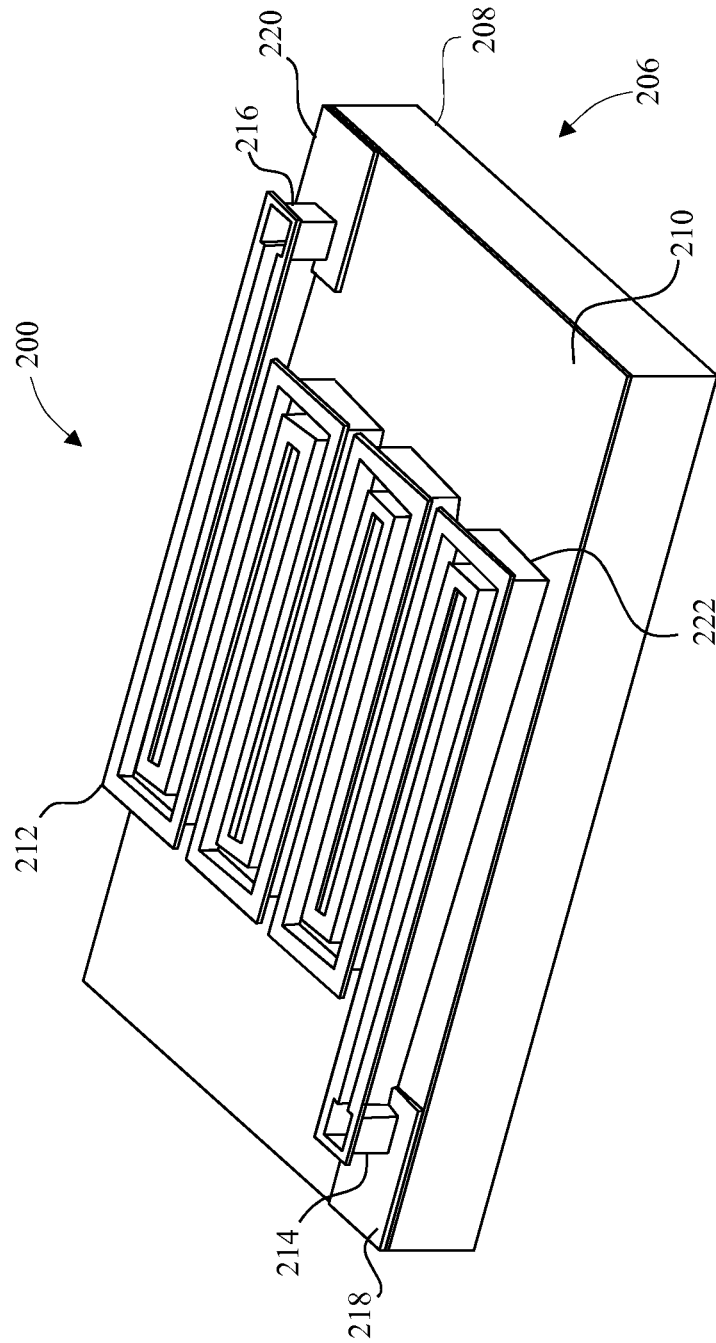


FIG. 8

1

THERMALLY SHORTED BOLOMETER**CROSS REFERENCE**

This application claims the benefit of U.S. Provisional Application No. 61/895,439 filed Oct. 25, 2013, the entire contents of which is herein incorporated by reference.

FIELD

This disclosure relates to sensor devices and methods of fabricating such devices.

BACKGROUND

Objects at any non-zero temperature radiate electromagnetic energy which can be described either as electromagnetic waves or photons, according to the laws known as Planck's law of radiation, the Stefan-Boltzmann Law, and Wien's displacement law. Wien's displacement law states that the wavelength at which an object radiates the most (λ_{max}) is inversely proportional to the temperature of the object as approximated by the following relation:

$$\lambda_{max}(\mu m) \approx \frac{3000}{T(K)}$$

Hence for objects having a temperature close to room temperature, most of the emitted electromagnetic radiation lies within the infrared region. Due to the presence of CO₂, H₂O, and other gasses and materials, the earth's atmosphere absorbs electromagnetic radiation having particular wavelengths. Measurements have shown, however, that there are "atmospheric windows" where the absorption is minimal. An example of such a "window" is the 8 μm -12 μm wavelength range. Another window occurs at the wavelength range of 3 μm -5 μm . Typically, objects having a temperature close to room temperature emit radiation close to 10 μm in wavelength. Therefore, electromagnetic radiation emitted by objects close to room temperature is only minimally absorbed by the earth's atmosphere. Accordingly, detection of the presence of objects which are either warmer or cooler than ambient room temperature is readily accomplished by using a detector capable of measuring electromagnetic radiation emitted by such objects.

Two types of electromagnetic radiation detectors are "photon detectors" and "thermal detectors". Photon detectors detect incident photons by using the energy of said photons to excite charge carriers in a material. The excitation of the material is then detected electronically. Thermal detectors also detect photons. Thermal detectors, however, use the energy of said photons to increase the temperature of a component. By measuring the change in temperature, the intensity of the photons producing the change in temperature can be determined.

In thermal detectors, the temperature change caused by incoming photons can be measured using temperature-dependant resistors (thermistors), the pyroelectric effect, the thermoelectric effect, gas expansion, and other approaches. One advantage of thermal detectors, particularly for long wavelength infrared detection, is that, unlike photon detectors, thermal detectors do not require cryogenic cooling in order to realize an acceptable level of performance.

One type of thermal sensor is known as a "bolometer." Even though the etymology of the word "bolometer" covers

2

any device used to measure radiation, bolometers are generally understood to be thermal detectors which rely on a thermistor to detect radiation in the long wavelength infrared window (8 μm -12 μm) or mid-wavelength infrared window (3 μm -5 μm).

The sensitivity of a bolometer generally increases with better thermal isolation of the sensor from its surroundings, with a higher infrared absorption coefficient, higher temperature coefficient of resistance, higher electrical resistance, and a higher bias current. Accordingly, because bolometers must first absorb incident electromagnetic radiation to induce a change in temperature, the efficiency of the absorber in a bolometer relates to the sensitivity and accuracy of the bolometer. Ideally, absorption as close to 100% of incident electromagnetic radiation is desired. In theory, a metal film having a sheet resistance (in Ohms per square) equal to the characteristic impedance of free space, laying over a dielectric or vacuum gap of optical thickness d will have an absorption coefficient of 100% for electromagnetic radiation of wavelength $4d$. The following relation shows the expression of the characteristic impedance (Y) of free space:

$$Y = \sqrt{\frac{\mu_0}{\epsilon_0}}$$

wherein ϵ_0 is the vacuum permittivity and μ_0 is the vacuum permeability.

The numerical value of the characteristic impedance of free space is close to 377 Ohm. The optical length of the gap is defined as "nd", where n is the index of refraction of the dielectric, air or vacuum.

In the past, micro-electromechanical systems (MEMS) have proven to be effective solutions in various applications due to the sensitivity, spatial and temporal resolutions, and lower power requirements exhibited by MEMS devices. One such application is as a bolometer. Known bolometers use a supporting material which serves as an absorber and as a mechanical support. Typically, the support material is silicon nitride. A thermally sensitive film is formed on the absorber to be used as a thermistor. The absorber structure with the attached thermistor is anchored to a substrate through suspension legs having high thermal resistance in order for the incident electromagnetic radiation to produce a large increase of temperature on the sensor.

The traditional technique used to micromachine suspended members involves the deposition of the material over a "sacrificial" layer, which is to be eventually removed and which is deposited, e.g., by spin coating or polymer coating using a photoresist. The deposition of the thin-film metal or semiconductor can be done with a variety of techniques including low-pressure chemical vapor deposition (LPCVD), epitaxial growth, thermal oxidation, plasma-enhanced chemical vapor deposition (PECVD), sputtering, and evaporation.

Most of the known bolometers, however, have a generally rectangular absorber. Such absorbers exhibit reduced thermal isolation and low electrical resistance, lowering the responsivity of the device. U.S. patent application Ser. No. 13/975,577, filed Aug. 26, 2013, the entire contents of which are herein incorporated by reference, discloses an infrared sensor with increased sensitivity and efficient thermal absorption. While very effective, the device in the '577 does present some challenges.

One challenge is in the manner of incorporating a reference sensor. When measuring the voltage change of a bolometer subject to an incident infrared radiation with an integrated

circuit, it is often beneficial to have reference sensors which do not react in the same way to infrared radiation to allow for a relative measurement. Such a reference sensor can be used to make the readout scheme more immune to process variations or temperature changes such as temperature changes of the substrate.

One approach to providing a reference sensor in known systems is to fabricate a sensor which is thermally shorted to the substrate. The substrate thus exchanges thermal energy with the sensor until the sensor has a temperature equal to the temperature of the substrate and the signal from the reference sensor can be used to correct for various errors. For traditional bolometer designs, which include a membrane suspended from the substrate by beams, a thermally shorted reference sensor is easily fabricated. Specifically, in the typical fabrication process a sensor membrane is released from the substrate by isotropically etching a sacrificial layer underneath the structure. Since the membrane size is significantly larger than the distance of the membrane to the substrate, release holes are included in the membrane to decrease the amount of underetch required to release the devices. The reference sensor is thus easily fabricated simply by omitting the release holes. With an appropriate etch time, the infrared sensors will be released while sacrificial material will remain between the reference sensor and the substrate, thermally shorting the reference sensor.

The known method of fabricating thermally shorted sensors as a reference sensor does not work with the devices disclosed in the '577 application. The serpentine structures disclosed in the '577 application are fabricated using a fast release etch without the requirement of release holes. As a result, the method of forming a reference sensor described above does not work for this improved structure.

It would be beneficial to provide a thermally shorted reference sensor that can be fabricated using the same manufacturing processes used in fabricating fast-release sensors. It would be advantageous if such a reference sensor could be fabricated while providing greater flexibility in the release etch time of the sensors.

SUMMARY

In one embodiment a MEMS sensor assembly includes a reference sensor with an absorber including a plurality of spaced apart conductive legs defining a tortuous path with a plurality of anchors provided along the tortuous path which thermally short the absorber to the substrate.

In another embodiment, a MEMS sensor assembly includes a reference sensor with an absorber having a plurality of spaced apart conductive legs defining a tortuous path with the absorber substantially continuously connected to the underlying substrate along the tortuous path.

In another embodiment, A MEMS sensor assembly includes a substrate, a first sensor supported by the substrate and including a first absorber spaced apart from the substrate, and a second sensor supported by the substrate and including (i) a second absorber spaced apart from the substrate, and (ii) at least one thermal shorting portion integrally formed with the second absorber and extending downwardly from the second absorber to the substrate thereby thermally shorting the second absorber to the substrate.

In one or more embodiments, the first absorber includes a plurality of spaced apart first conductive legs defining a first tortuous path across a first area above the substrate, the second absorber includes a plurality of spaced apart second conductive legs defining a second tortuous path across a second area above the substrate, and the at least one thermal

shorting portion extends downwardly from at least one of the plurality of spaced apart second conductive legs.

In one or more embodiments, the at least one thermal shorting portion comprises a single thermal shorting leg extending downwardly from each of the plurality of spaced apart second conductive legs.

In one or more embodiments, the at least one thermal shorting portion comprises a plurality of thermal shorting legs, each of the plurality of thermal shorting legs extending downwardly from a respective one of the plurality of spaced apart second conductive legs.

In one or more embodiments, the at least one thermal shorting portion comprises a plurality of thermal shorting legs, each of the plurality of thermal shorting legs associated with a respective two of the plurality of spaced apart second conductive legs.

In one or more embodiments, the at least one thermal shorting portion directly contacts an upper surface of the substrate.

In one or more embodiments, the assembly includes a first conductive pad in electrical communication with the second absorber, the first conductive pad formed on an upper surface of an insulator layer of the substrate, and the at least one thermal shorting portion directly contacts a second conductive pad formed on an upper surface of an insulator layer of the substrate and electrically isolated from the first conductive pad.

In one or more embodiments, the at least one thermal shorting portion includes a hollow thermal shorting post.

In one or more embodiments, each of the plurality of spaced apart second conductive legs comprises a plurality of layers.

In one or more embodiments, the plurality of layers comprise a substrate layer, a first conductive layer on an upper surface of the substrate layer, and an insulation layer on an upper surface of the conductive layer, and the at least one thermal shorting portion comprises a second conductive layer integrally formed with the first conductive layer.

In another embodiment, a method of forming a MEMS sensor assembly includes providing a substrate layer, supporting a first absorber with the substrate at a first location spaced apart from the substrate, supporting a second absorber with the substrate at a second location spaced apart from the substrate, and integrally forming at least one thermal shorting portion with the second absorber, the at least one thermal shorting portion extending downwardly from the second absorber to the substrate thereby thermally shorting the second absorber to the substrate.

In one or more embodiments, providing a substrate layer includes providing an insulator layer on an upper surface of a handle layer, the method further including forming a pair of electrical contacts on an upper surface of the insulating layer, and placing the electrical contacts in electrical communication with the second absorber.

In one or more embodiments, integrally forming at least one thermal shorting portion includes forming a sacrificial layer on respective upper surfaces of the pair of electrical contacts and on the upper surface of the insulating layer, etching at least one trench completely through the sacrificial layer to expose portions of the insulating layer, and depositing a conductive layer along a wall of the at least one trench while depositing second absorber material above an upper surface of the sacrificial layer.

In one or more embodiments, a method includes forming a serpentine trench in the sacrificial layer, wherein depositing the conductive layer along the wall of the at least one trench

5

includes depositing the conductive layer along the wall of the at least one trench while depositing second absorber material within the serpentine trench.

In one or more embodiments, depositing the conductive layer along the wall of the at least one trench further includes depositing the conductive layer along the wall of the at least one trench while depositing second absorber material within the serpentine trench by atomic layer deposition (ALD).

In one or more embodiments, depositing the conductive layer along the wall of the at least one trench further includes depositing the conductive layer on the wall of the at least one trench to form a hollow post.

In one or more embodiments, depositing the conductive layer along the wall of the at least one trench further includes depositing the conductive layer on an insulating layer formed along the wall of the at least one trench.

In one or more embodiments, a method includes forming an insulating layer on the conductive layer deposited along the wall of the at least one trench.

In one or more embodiments, a method includes etching the sacrificial layer after depositing the conductive layer.

In one or more embodiments, etching at least one trench completely through the sacrificial layer includes etching a serpentine trench completely through the sacrificial layer to expose portions of the insulating layer and portions of the pair of electrical contacts.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 depicts a top perspective view of a bolometer sensor assembly including a bolometer sensor and a thermally shorted reference sensor in accordance with principles of the disclosure;

FIG. 2 depicts a top perspective view of the thermally shorted reference sensor of FIG. 1;

FIG. 3 depicts a side cross-sectional view of a device substrate which in this embodiment is a complementary metal oxide semiconductor (CMOS), with an insulator layer formed on the substrate in accordance with principles of the disclosure;

FIG. 4 depicts a side cross-sectional view of the device of FIG. 3 after electrical contacts have been formed on the insulator layer;

FIG. 5 depicts a side cross-sectional view of the device of FIG. 4 after a sacrificial layer has been formed above the electrical contacts;

FIG. 6 depicts a side cross-sectional view of the device of FIG. 5 with trenches formed through the sacrificial layer to expose the electrical pads and a portions of the insulator layer;

FIG. 7 depicts a side cross-sectional view of the device of FIG. 6 with an absorber layer formed on the exposed surfaces; and

FIG. 8 depicts a top perspective view of a thermally shorted reference sensor in accordance with principles of the disclosure.

DESCRIPTION

For the purposes of promoting an understanding of the principles of the disclosure, reference will now be made to the embodiments illustrated in the drawings and described in the following written specification. It is understood that no limitation to the scope of the disclosure is thereby intended. It is further understood that the disclosure includes any alterations and modifications to the illustrated embodiments and

6

includes further applications of the principles of the disclosure as would normally occur to one skilled in the art to which this disclosure pertains.

A semiconductor sensor assembly **100** is depicted in FIG. 1. The sensor assembly **100** includes a bolometer sensor **102** and a thermally shorted reference bolometer sensor **104** upon a common substrate **106**. The substrate **106** in one embodiment is a complementary metal oxide semiconductor (CMOS) substrate or another type of substrate and includes a handle layer **108** and an insulator layer **110**. The substrate **106** in some embodiments includes the electronic circuitry used to access the output of the sensor assembly **100**. The insulator layer **110** in one embodiment is a deposited dielectric like, e.g., SiO₂.

The sensor **102** includes an absorber **112** which is supported by two support posts **114** and **116**. A mirror (not shown) may be located beneath the absorber **112**. Two conductive pads **118** and **120** provide electrical connectivity with the support posts **114/116**, respectively. Because the only connection between the absorber **112** and the substrate **106** is at the support posts **114** and **116**, the absorber **112** is effectively thermally isolated from the substrate **106**. In other embodiments, the absorber has a different shape such as, for example, a square or other shape or pattern.

The absorber **112** is a free-standing serpentine wire structure. The free-standing serpentine wire structure provides better thermal isolation and higher electrical resistance (and therefore a higher responsivity) without an increase in size over typical absorber structures which are generally rectangular. For example, the serpentine nature of the absorber **112** increases the lineal distance along the absorber **112** between the posts **114/116** by a factor of over 5 compared to a rectangular absorber.

The absorber **112**, in addition to absorbing energy from incident photons, is selected to provide a good noise-equivalent temperature difference (NETD). In order for the absorber **112** to have a good NETD, the material selected to form the absorber **112** should exhibit a high temperature coefficient of resistance while exhibiting low excess noise (1/f noise). Semiconductor materials such as vanadium oxide are common in micromachined bolometers due to their high temperature coefficient of resistance. Other materials include Si (poly/amorphous), SiGe, Ge, Pt, TiN, Ti, and combinations of the foregoing. While metals have a lower temperature coefficient of resistance than some semiconductor materials, such as vanadium oxide, metals typically have much lower excess noise than many semiconductor materials, thus offering better NETD.

Accordingly, in one embodiment the absorber **112** comprises metal. Titanium and Platinum are two metals which exhibit desired characteristics. Titanium, for example, exhibits a bulk resistivity of about 7×10^{-7} Ohm. Using a bulk resistivity of 7×10^{-7} Ohm, the thickness of the absorber **112** needed to match the impedance of free-space (377 Ohm/square) should be about 1.9 nm. The resistivity of materials formed to a thickness less than about 50 nm, however, can be several times higher than the bulk value. Accordingly, depending on process parameters, the thickness of the absorber **112**, if made from titanium, is preferably about 10 nm. Impurities can also be introduced into the absorber **112** during formation in order to tune the resistivity if needed.

The reference sensor **104** is also shown in FIG. 2. The reference sensor **104** includes an absorber **130** which is supported by two support posts **132** and **134**. Two conductive pads **136** and **138** provide electrical connectivity with the support posts **132/134**, respectively. If desired, a mirror may be positioned beneath the absorber **130**. In the foregoing

respects, the reference sensor **104** is identical to the sensor **102**. The reference sensor **104** further includes, however, a number of shorting posts **140**. As depicted in FIG. 2, each of the thermal shorting posts **140** is associated with a pair of legs **142**.

The shorting posts **140** are formed using the same process steps used to form the supporting posts **132** and **134** with the exception that the shorting posts **140** in this embodiment are formed directly upon the upper surface of the insulator layer **110**. This is easily accomplished by simply omitting the formation of a conductive pad such as the conductive pads **136/138** under the shorting posts **140** as discussed in further detail below. The shorting posts **140** are thus electrically isolated from the conductive pads **136** and **138**, but provide a thermal conducting path between the substrate **106** and the absorber **112**.

In other embodiments, the shorting posts **140** terminate at the same layer as the conductive pads **136**. In such embodiments, the areas supporting the posts can be isolated areas or one connected area of the conductive material formed. The shorting posts can be floating or electrically connected, e.g. to ground or to the same potential as one of the pads **136/138**. Therefore the identical process flow can be used as is used for forming the contact/supporting posts **132/134**.

In some embodiments, the shorting posts **140** extend into the handle layer **108**. Additionally, while six shorting posts **140** are depicted in FIG. 2, more or fewer posts are used in other embodiments to provide a desired amount of thermal conductivity. Moreover, while the shorting posts in FIG. 2 are positioned at the ends of the seven absorber legs **142**, the shorting posts in other embodiments are additionally or alternatively positioned along the absorber legs. The shorting posts in the other embodiments would thus be associated with a single absorber leg.

Because the absorber **130** and support posts **132/134** of the reference sensor **104** are substantially identical to the absorber **112** and support posts **114/118**, and because the shorting posts are configured to have minimal impact on the overall electrical characteristics of the reference sensor **104**, the reference sensor **104** and sensor **102** share the same electrical characteristics. The increased sensitivity of the sensor **104** to the temperature of the substrate **106** through the shorting posts **140**, however, allows a relative measurement of the resistance change caused by substrate temperature with an integrated circuit. The signal from the reference sensor **104** is thus used to suppress influences of process variations and cross-sensitivity to e.g. substrate temperature changes.

Returning to FIG. 1, the total resistance for the sensor **102** measured across the support posts **114/116** and the absorber **112** is defined by the following equation:

$$R = n * R_a$$

where n is the number of linear leg portions and R_a is the resistance of one of the linear leg portions, which together form the absorber **112**. The resistance of the support posts **114/116** is de minimis because of the relatively large bulk of material and the short length compared to the support leg portions.

Upon impingement of the absorber **112** with electromagnetic radiation, the average temperature of the absorber **112** increases by ΔT . The electrical resistance of the sensor upon incident radiation changes by an amount ΔR given by:

$$\Delta R = \alpha n R_a \Delta T$$

where α is the temperature coefficient of resistance of the thin film.

In one embodiment, the width of the linear leg portion is significantly smaller than the wavelength of the infrared radiation to be measured (8 μm -12 μm or 3 μm -5 μm) (also referred to as the "target" wavelength). Therefore, the assembly of linear leg portions is seen as an effective medium by the incoming infrared radiation and forms an efficient absorber.

In one embodiment, the gaps between the linear leg portions is significantly smaller than the target wavelength (8 μm -12 μm or 3 μm -5 μm). Therefore, the assembly of linear leg portions as a total are seen as an effective medium by the incoming infrared radiation and forms an efficient absorber. Thus, the incoming IR radiation sees an increased effective sheet resistance and the aforementioned 377 ohm condition can be achieved with higher film thicknesses.

When electromagnetic radiation (e.g. infrared light) reaches the sensor assembly **102**, the electromagnetic radiation is absorbed within the thin-film metal of the absorber **112** with an efficiency depending on the resistivity of the absorber **112**, quality of the mirror (not shown), gap height between the absorber **112** and the mirror, and radiation wavelength. Upon absorbing the incident radiation, the absorber **112** undergoes an increase in temperature. This temperature increase, in turn, leads to either a decrease or increase of the resistivity of the absorber **112**. The absorber **112** is then electrically probed to measure the resistivity of, and thus indirectly measure the amount of incident electromagnetic radiation on, the absorber **112**.

The reference sensor **104** operates in substantially the same manner as the sensor **102**. The main difference is that the thermal resistance of the absorber to the substrate is significantly smaller. For a given power of infrared radiation impinging on the absorber, the temperature increase of the absorber (ΔT) is therefore significantly smaller. With a favorable layout of the shorting posts **140**, the temperature difference caused by the infrared radiation can be made negligible. Then, the temperature of the absorber **130** is dominated by the temperature of the substrate **106** which is transferred to the absorber **130** by the shorting posts **140**. The signal from the reference sensor **104** is then used to compensate for thermal conditions in the substrate and/or other influences of process variations and cross-sensitivity.

Fabrication of a sensor assembly such as the sensor assembly **100** begins with preparation of a substrate **150** which is shown in FIG. 3. While the following description highlights formation of the reference sensor, the bolometer sensor is formed simultaneously and substantially as described except where noted. The substrate **150** may be a portion of a larger substrate that is used to form a number of sensors and reference sensors. An insulator layer portion **152** is formed on the upper surface of the substrate **150**. In this example, an oxide film of about 1000 Å is formed on the substrate **150**.

Next, electrical contacts **154** and **156** are formed on the upper surface of the insulator layer portion **152** (FIG. 4). The electrical contacts **154/156** are formed from a conducting metal by any acceptable process such as one incorporating lithography and plasma etching. A sacrificial layer **162** is then formed thereby encapsulating the electrical contacts **154/156** (FIG. 5). The sacrificial layer **162** may be planarized if desired.

Openings **186** and **188** are formed by etching trenches completely through the sacrificial layer **162** to expose portions of the electrical contacts **154** and **156**, respectively (FIG. 6). Trenches **190** are also formed. The trenches **190** extend completely through the sacrificial layer **162**. In areas of the substrate **150** used for bolometer sensors, the formation of the trenches **190** is omitted. A serpentine trench (not shown) is then formed in the sacrificial layer **162** connecting the open-

ings **186**, **188** and **190**. The openings **186/188/190** and the trench (not shown) may be formed using spin photoresist and lithography, for example.

An absorber layer **192** (see FIG. 7) is then formed on the exposed surfaces of the openings **186/188/190** and the trench (not shown). The absorber layer **192** in some embodiments is formed by atomic layer deposition (ALD). ALD is used to deposit materials by exposing a substrate to several different precursors sequentially. A typical deposition cycle begins by exposing a substrate to a precursor "A" which reacts with the substrate surface until saturation. This is referred to as a "self-terminating reaction." Next, the substrate is exposed to a precursor "B" which reacts with the surface until saturation. The second self-terminating reaction reactivates the surface. Reactivation allows the precursor "A" to react with the surface. Typically, the precursors used in ALD include an organometallic precursor and an oxidizing agent such as water vapor or ozone.

The deposition cycle results, ideally, in one atomic layer being formed. Thereafter, another layer may be formed by repeating the process. Accordingly, the final thickness of the absorber layer **192** is controlled by the number of cycles a substrate is exposed to. Moreover, deposition using an ALD process is substantially unaffected by the orientation of the particular surface upon which material is to be deposited. Accordingly, an extremely uniform thickness of material may be realized both on the horizontal surfaces (the insulator layer portion **152**, the exposed surface portions of the electrical contacts **154/156**, and the bottom of the serpentine trench) and on the vertical surfaces (the sides of the openings **186** and **188**, the walls of the trenches **190**). Thus, in some embodiments the posts **114/116/132/134** and shorting posts **140** are hollow, and may be further anchored as described in U.S. patent application Ser. No. 13/415,479, filed Mar. 8, 2012, the entire contents of which are herein incorporated by reference.

In some embodiments, it may be desired to form structures using multiple layers of ALD material. For example, while the device in the example includes a single absorber layer **192**, a stacked absorber may be useful in different embodiments. A stacked absorber or other structure may have two, three, or more layers of different or alternating materials. For example, a layer of insulating material may provide a substrate for a layer of a conducting material with yet another insulating material above the conducting material. A very thin conducting layer may thus be protected and strengthened by being sandwiched between two very thin insulating layers. Al_2O_3 may be used as an insulating layer deposited using ALD.

Once the absorber layer **192** is formed, portions of the absorber layer **192** may be removed to provide the desired shape of the absorber and the sacrificial layer **162** is then etched to form the final device, such as the sensor assembly **100** of FIG. 1.

The above described process discloses a method to fabricate a reference bolometer which is thermally shorted to the substrate by including additional structures (e.g. shorting posts) which are in contact with an electrically isolating part of the substrate. The process in different embodiments is modified for a particular application. For example, FIG. 8 depicts a reference sensor **200** that in some embodiments is included in the sensor assembly **100** of FIG. 1. The reference sensor **200** includes a substrate **206** with a handle layer **208** and an insulator layer **210**. The reference sensor **200** includes an absorber **212** which is supported by two support posts **214** and **216**. Two conductive pads **218** and **220** provide electrical connectivity with the support posts **214/216**, respectively.

In place of six discrete shorting posts such as the shorting posts **140**, the reference sensor **200** includes a single shorting post **222** which extends along the entire length of the absorber **112**. The shorting post **222** functions in the same manner as the shorting posts **140**. Like the shorting posts **140**, the shorting post **222** can be formed without adding any steps to a forming process used to form a sensor such as the sensor **102**. For example, the shorting post **222** in one embodiment is formed using essentially the same process described above. The difference being that instead of forming the trenches **190** which are used to form the support posts **140**, the serpentine trench (not shown) used to form the serpentine absorber is extended down to the upper surface of the insulator layer **152**.

Accordingly, the above disclosure provides a reference sensor in assemblies including fast-etch absorbers without adding processing steps. The disclosed method offers greater flexibility in the release etch time as the formation of the thermally shorted bolometer does not depend on a timed etch.

Moreover, while the absorbers in the above described embodiments are generally "U" shaped, other forms can be incorporated with the above described shortening posts such as those forms disclosed in the '577 application as well as forms disclosed in U.S. patent application Ser. No. 13/415,479, filed Mar. 8, 2012, the entire contents of which are herein incorporated by reference. Additionally, the processes in the '577 application and the '479 application can be modified to provide shorting posts using the procedures discussed above.

The disclosure thus provides a bolometer that is thermally shorted to the substrate with a serpentine-like absorber structure instead of a membrane. The disclosed reference structure provides the same electrical resistance as the functional bolometer in the assembly. By the incorporation of multiple of the described reference structures over a bolometer chip, the reference sensors are used in some embodiments to sense gradients e.g. in process variations or substrate temperature. The disclosed reference structures can be used in Wheatstone bridges together with functional bolometers or other electrical circuits used to reduce measurement offsets.

While the disclosure has been illustrated and described in detail in the drawings and foregoing description, the same should be considered as illustrative and not restrictive in character. It is understood that only the preferred embodiments have been presented and that all changes, modifications and further applications that come within the spirit of the disclosure are desired to be protected.

The invention claimed is:

1. A MEMS sensor assembly comprising:

a substrate;

a first sensor supported by the substrate and including a first absorber spaced apart from the substrate; and

a second sensor supported by the substrate and including (i) a second absorber spaced apart from the substrate, (ii) two support posts supporting the absorber above the substrate and in electrical communication with the absorber, and (iii) at least one thermal shorting portion integrally formed with the second absorber, the at least one thermal shorting portion extending downwardly from the second absorber toward the substrate at a location between the two support posts and configured to thermally short the second absorber to the substrate.

2. The MEMS sensor assembly of claim 1, wherein:

the first absorber includes a plurality of spaced apart first conductive legs defining a first tortuous path across a first area above the substrate;

the second absorber includes a plurality of spaced apart second conductive legs defining a second tortuous path across a second area above the substrate; and

11

the at least one thermal shorting portion extends downwardly from at least one of the plurality of spaced apart second conductive legs.

3. The MEMS sensor assembly of claim 2, wherein the at least one thermal shorting portion comprises a single thermal shorting leg extending downwardly from each of the plurality of spaced apart second conductive legs.

4. The MEMS sensor assembly of claim 2, wherein the at least one thermal shorting portion comprises a plurality of thermal shorting legs, each of the plurality of thermal shorting legs extending downwardly from a respective one of the plurality of spaced apart second conductive legs.

5. The MEMS sensor assembly of claim 2, wherein the at least one thermal shorting portion comprises a plurality of thermal shorting legs, each of the plurality of thermal shorting legs associated with a respective two of the plurality of spaced apart second conductive legs.

6. The MEMS sensor assembly of claim 5, wherein:
the plurality of layers comprise a substrate layer, a first conductive layer on an upper surface of the substrate layer, and an insulation layer on an upper surface of the conductive layer; and

the at least one thermal shorting portion comprises a second conductive layer integrally formed with the first conductive layer.

7. The MEMS sensor assembly of claim 2, wherein the at least one thermal shorting portion directly contacts an upper surface of the substrate.

8. The MEMS sensor assembly of claim 7, wherein:
the assembly includes a first conductive pad in electrical communication with the second absorber, the first conductive pad formed on an upper surface of an insulator layer of the substrate; and

the at least one thermal shorting portion directly contacts a second conductive pad formed on an upper surface of an insulator layer of the substrate and electrically isolated from the first conductive pad.

9. The MEMS sensor assembly of claim 2, wherein the at least one thermal shorting portion comprises:
a hollow thermal shorting post.

10. The MEMS sensor assembly of claim 9, wherein each of the plurality of spaced apart second conductive legs comprises a plurality of layers.

11. A method of forming a MEMS sensor assembly comprising:

providing a substrate layer;

supporting a first absorber with the substrate at a first location spaced apart from the substrate with a first pair of support posts in electrical communication with the first absorber;

supporting a second absorber with the substrate at a second location spaced apart from the substrate with a second pair of support posts in electrical communication with the second absorber; and

integrally forming at least one thermal shorting portion with the second absorber, the at least one thermal shorting portion extending downwardly from the second

12

absorber toward the substrate thereby thermally shorting the second absorber to the substrate.

12. The method of claim 11, wherein providing a substrate layer comprises providing an insulator layer on an upper surface of a handle layer, the method further comprising:

forming a pair of electrical contacts on an upper surface of the insulating layer; and

placing the electrical contacts in electrical communication with the second absorber through the second pair of support posts.

13. The method of claim 12, wherein integrally forming at least one thermal shorting portion comprises:

forming a sacrificial layer on respective upper surfaces of the pair of electrical contacts and on the upper surface of the insulating layer;

etching at least one trench completely through the sacrificial layer to expose portions of the insulating layer; and depositing a conductive layer along a wall of the at least one trench while depositing second absorber material above an upper surface of the sacrificial layer.

14. The method of claim 13, further comprising:

forming a serpentine trench in the sacrificial layer, wherein depositing the conductive layer along the wall of the at least one trench comprises:

depositing the conductive layer along the wall of the at least one trench while depositing second absorber material within the serpentine trench.

15. The method of claim 14, wherein depositing the conductive layer along the wall of the at least one trench further comprises:

depositing the conductive layer along the wall of the at least one trench while depositing second absorber material within the serpentine trench by atomic layer deposition (ALD).

16. The method of claim 15, wherein depositing the conductive layer along the wall of the at least one trench further comprises:

depositing the conductive layer on the wall of the at least one trench to form a hollow post.

17. The method of claim 15, wherein depositing the conductive layer along the wall of the at least one trench further comprises:

depositing the conductive layer on an insulating layer formed along the wall of the at least one trench.

18. The method of claim 17, further comprising:

forming an insulating layer on the conductive layer deposited along the wall of the at least one trench.

19. The method of claim 18, further comprising:

etching the sacrificial layer after depositing the conductive layer.

20. The method of claim 12, wherein etching at least one trench completely through the sacrificial layer comprises:

etching a serpentine trench completely through the sacrificial layer to expose portions of the insulating layer and portions of the pair of electrical contacts.

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